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# Analog Layout Techniques

## EE5325 Power Management Integrated Circuits

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IIT Madras**

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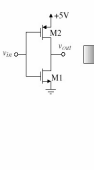


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## Introduction

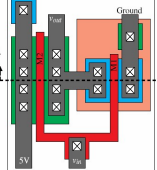
- The layout design is the representation of electrical design in form of many distinct geometrical rectangles at various level
- The layout is used to create the mask that enables the fabrication of chip

**CIRCUIT**

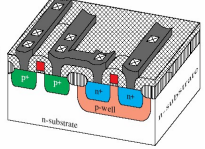


**LAYOUT**

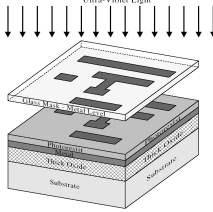
Blue	Green	Black	Red	Orange	White
p+	p-	Metal	Poly	p-well	n-substrate




**FABRICATION**



Ultra-Violet Light



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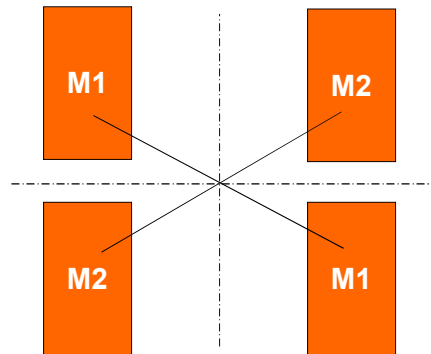


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## Device Matching

- Common centroid: common centroid technique is used to compensate the mismatch in devices due to non-idealities of process and operating conditions.

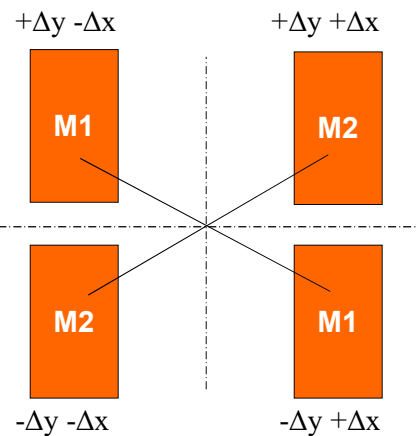


All the matched devices are placed along diagonals in such a ways that all the diagonals should intersect at the centre.



## Device Matching

- How the variations are cancelled out



Assuming the variation in y-axis is  $\pm\Delta y$  and in x-axis is  $\pm\Delta x$

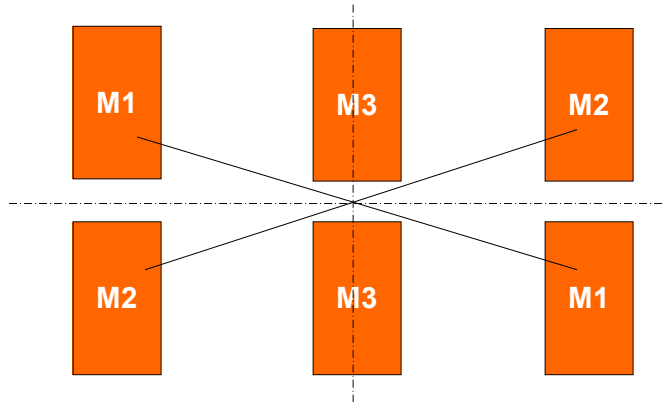
Total variation in M1:  
 $= +\Delta y - \Delta x - \Delta y + \Delta x = 0$

Total variation in M2:  
 $= +\Delta y + \Delta x - \Delta y - \Delta x = 0$



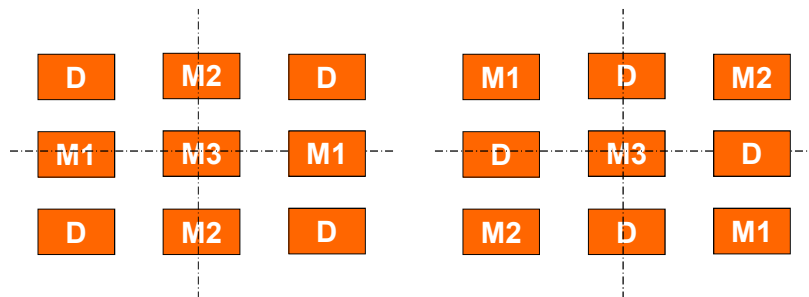
## Device Matching

- Common centroid for three matched devices



## Device Matching

- Common centroid for unequal number of devices

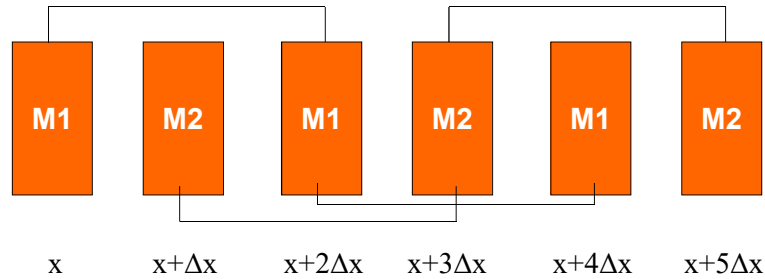


Dummy device D are inserted for proper matching



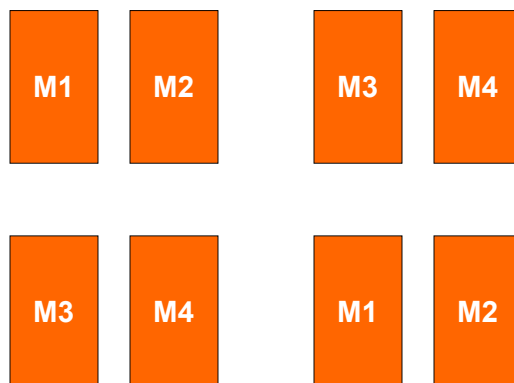
## Device Matching

- Intergitized layout: the cells are placed in alternate order to average out the variation
  - Generally used when less no. of devices are to be matched ( 2 or 3 )



## Device Matching

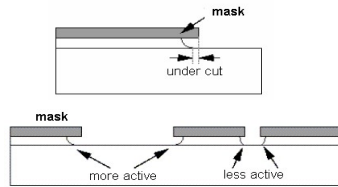
- Combination of common centroid and Intergitized layout could also be used



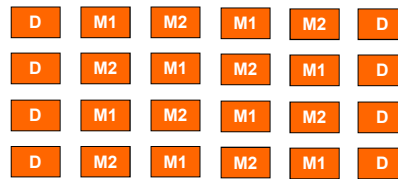
## Device Matching

### ▪ Dummy cells

- Mismatch occurs due to boundary dependant etching, CMP and doping
- Addition of dummy cells at the boundary helps in improving matching.
- All the matched devices see same adjacent structure



Edge effect during etching



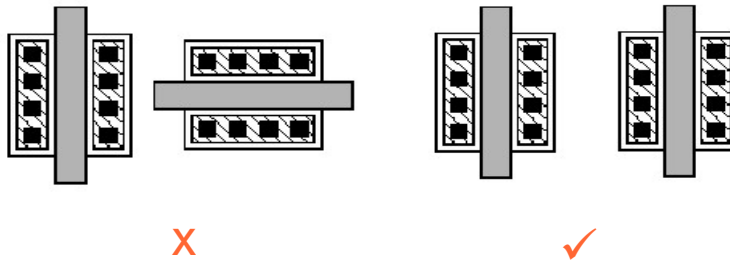
Use of dummy cells to avoid effect in matched devices



## Device Matching

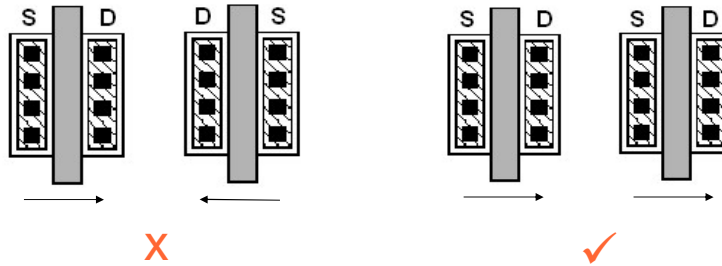
### ▪ Orientation

- Matched devices should have identical orientation



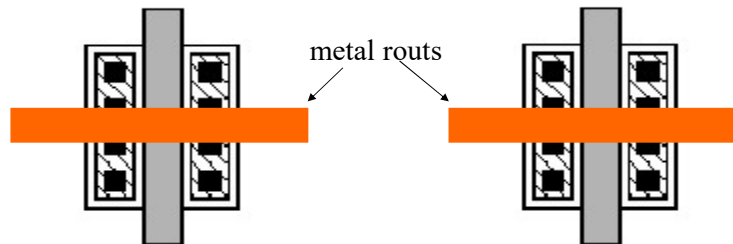
## Device Matching

- Direction of current
  - Matched devices should have the same direction of current flow



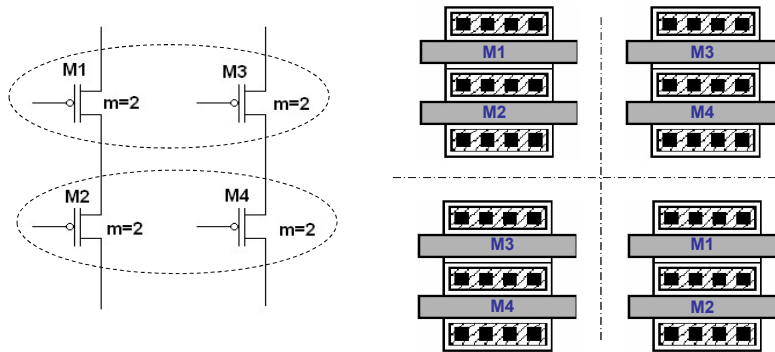
## Device Matching

- Dummy routs: if a signal is routed over one device then identical dummy rout should be put on the other device



## Device Matching

- Layout of matched cascode devices



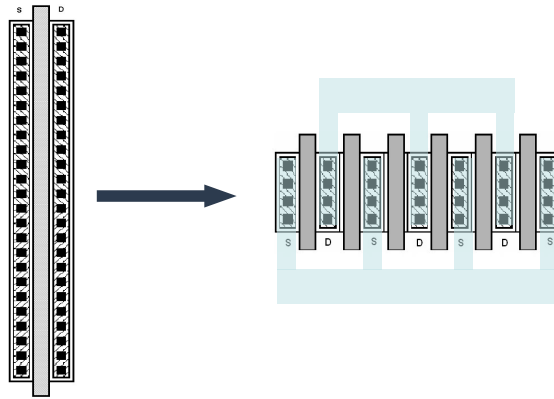
## Device Matching

- Guidelines for matching
  - Use multiple number of devices with same unit size and change multiplier as per the requirement
  - Use interdigitated or common centroid
  - Even number of multipliers help in better matching
  - Dummy cells should be used at boundary to take out the edge effect
  - Use antenna diodes(diffusion) at the gate of matched devices to avoid  $V_t$  mismatch due to charge injection
  - Don't rout voltages a long way – IR drops can cause big mismatch
  - Matched signals should be routed together and in the same metal
  - Matched devices should be palced in close proximity
  - Don't use cells with very small W & L as they may cause bigger mismatch
  - Routing should be avoided over the gate of critically matched transistors



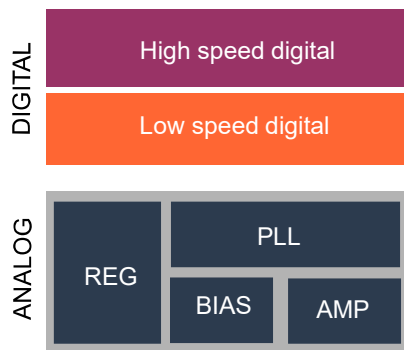
## Fingering of transistors

- The multi finger technique enables the sharing of drain/source hence reducing the parasitic caps
- Reduces the gate resistance – helps in fast charging



## Placement

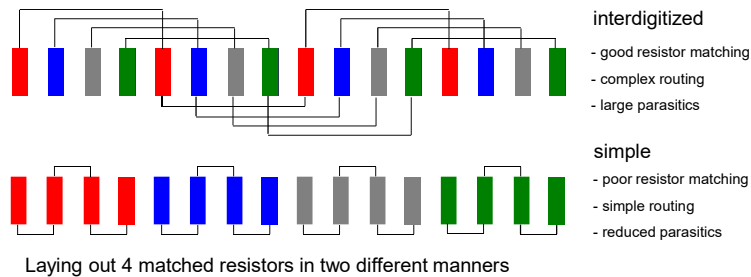
- All the analog should be placed together
- Separate the analog and digital blocks as much as possible
- Should be kept away from switching I/Os
- It is preferable to keep the regulator near supply pad to minimize the ESR of external de-cap





## Laying out Resistors

- Matching techniques should be used for critically matched resistors and capacitors
- Head contacts should be increased to reduce the mismatch due to contact resistance
- Special care should be taken while routing of matched resistors/capacitors to avoid any mismatch due to routings
- For timing critical applications, sometimes common centroid/interdigitized is not preferred because of routing parasitic – A simple straight method is used



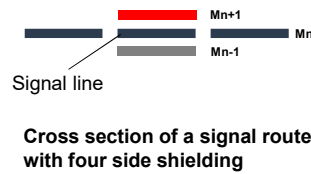
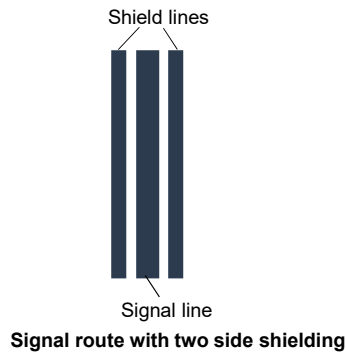
## Guidelines for Resistors and capacitors

- For proper matching the size of resistors and capacitors should not be too small
- The matched capacitors and resistors should be placed closely but minimum spacing is required to avoid any kind of signal coupling if there is any
- For fringe caps it's recommended to use odd number of fingers
- Always use dummy capacitors and resistors at boundaries to avoid edge effect



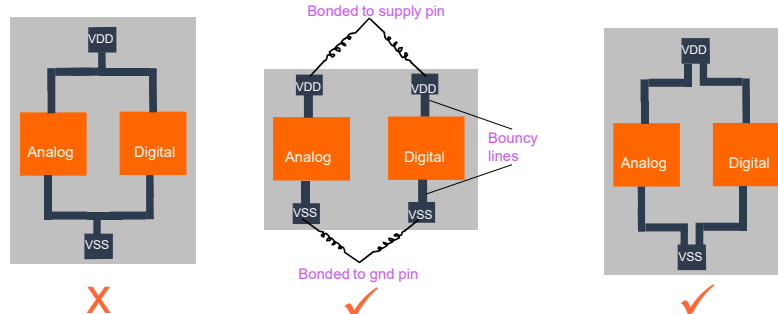
## Noise decoupling and shielding

- All the critical signals should be shielded with gnd or clean reference signal
- For high speed signals, the shield line shouldn't be put closer to the signal to avoid loading
- Use proper spacing between two signal



## Noise decoupling and shielding

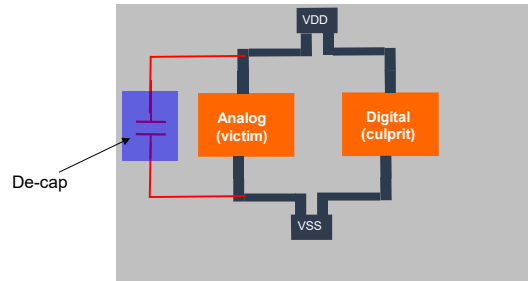
- Supply and ground routings
  - Digital and analog blocks should have separate supply and ground pads to minimize the ground/supply noise due to  $Ldi/dt$  and IR drops
  - If separate pads are not possible then the two supplies should be star connected from pad



## Noise decoupling and shielding

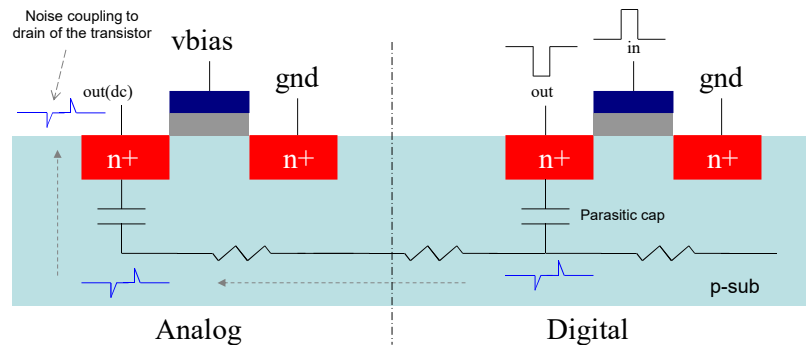
- Decoupling caps

- Decoupling caps helps in filtering supply noise caused by switching
- On-chip de-caps are more effective as they are more closure to the both culprit and victim hence have lower ESR
- De-caps should be put as close as possible to prevent it from propagating further. It should be ensured to connect the decap with reference to clean gnd.



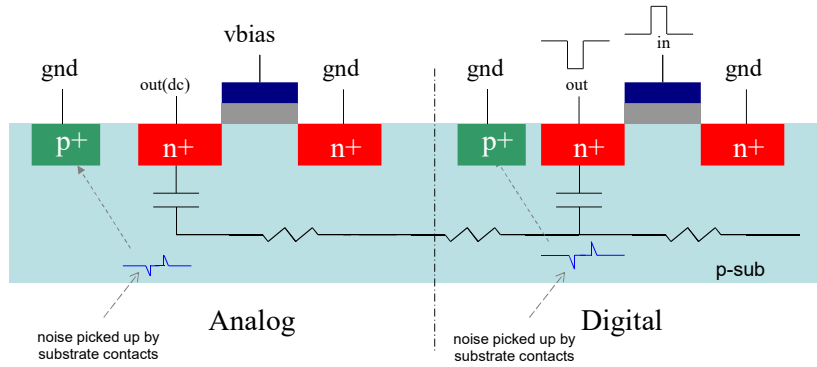
## Noise decoupling and shielding

- Substrate noise causes  $V_t$  modulation due to body effect
- Substrate and well ties (guard rings) should be added to reduce the substrate noise
- Can be reduced by increasing the spacing between sensitive analog and switching digital blocks



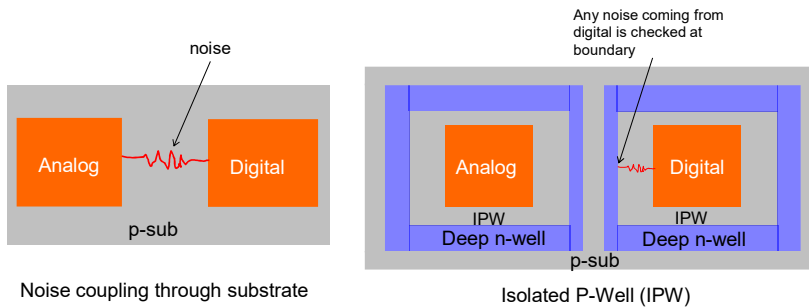
## Noise decoupling and shielding

- Substrate tie provides a low resistive path and the noise is picked-up thus avoiding any coupling with the signal



## Noise decoupling and shielding

- Isolated P-Well**
  - Noise gets propagated through substrate as all the modules sits on a common sub
  - For better isolation modules can be put in separate p-wells
  - If possible put both analog as well as digital in IPWs
  - Use separate gnd connections for both the IPWs



## Latchup guidelines

- Large area of well should not be left without ties – put as much ties as possible
- All p-type devices should be placed together and kept apart from n-type devices
- Double guard bar (both p and n) provides better immunity to latchup
- Floating bodies are prone to latchup – if putting the devices in IPW, make sure they are tied to gnd
- Supply and GND resistance should be as low as possible. If there is scope then stack supply and gnd line with multiple metals. Low GND resistance also enhances ESD
- If ESDs are sandwiched between two pads then makes sure that pmos faces pmos and nmos to nmos. The placement pattern should be

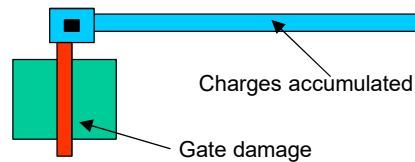
Or  
 NMOS ESD1- PAD1 – PMOS ESD1 – PMOS ESD2 – PAD2 – NMOS ESD2  
 PMOS ESD1- PAD1 – NMOS ESD1 – NMOS ESD2 – PAD2 – PMOS ESD2

Avoid using the pattern: NMOS ESD1- PAD1 – PMOS ESD1 – NMOS ESD2 – PAD2 – PMOS ESD2



## Antenna Effect

- During fabrication, plasma etching charges metal lines
- Degrades MOS  $V_t$ , or damage gate oxide



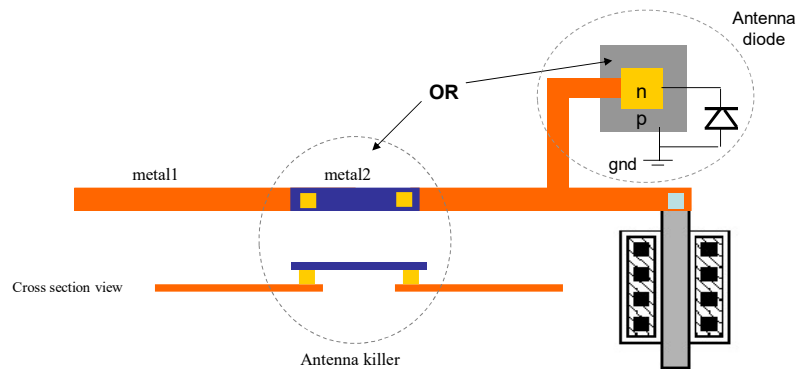
$$\text{Antenna ratio} = \text{Area (metal)} / \text{Area (gate)} < 70 \text{ (0.13}\mu\text{m process)}$$

Although, rule for antenna ratio is technology dependent but should always be kept as low as possible



## Antenna Guidelines

- Addition of antenna diode(p/n diffusion) prevents the gate damage due to charge injection by dissipating the charge
- The ratio of metal/gate poly area should be kept low to avoid the antenna effect
- Metal jumpers are used as antenna killers
- Large diodes are not used on high speed circuits to avoid the loading



## Electromigration

- Electromigration – higher flow of current through metal may cause melting of metal
- May be caused due to both peak as well as dc/avg current
- Width of the routes should be calculated as per the current
- Fingering/splitting of devices helps in improving electromigration
- Supply and gnd lines should be routed in higher metal and if possible stack with multiple metals
- High current lines shouldn't be routed a long way – place the module as close as possible to the source/sink
- 90deg bend in high current lines should be avoided – if process allows then use 45deg bend

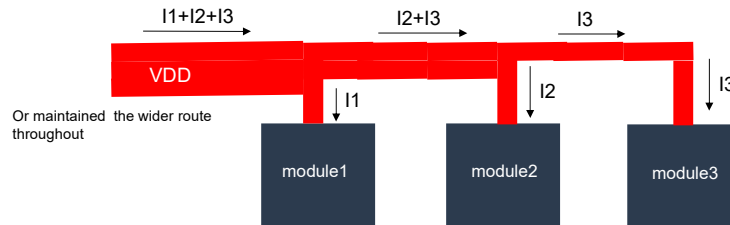


Bending of a high current line



## Electromigration

- For feeding multiple modules, the main supply width should be multiplied with the no. of modules



## Tiling methodology

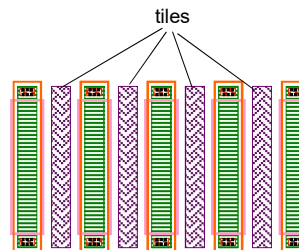
- Used to protect the oxide during CMP
- Tiles should be distributed evenly rather than concentrating in one area
- Automatic tiling is random so should be avoided for critically matched devices
- Tiling of matched devices should be taken care at module level and always done manually
- Stacking of metals helps in meeting tiling requirement



X



✓

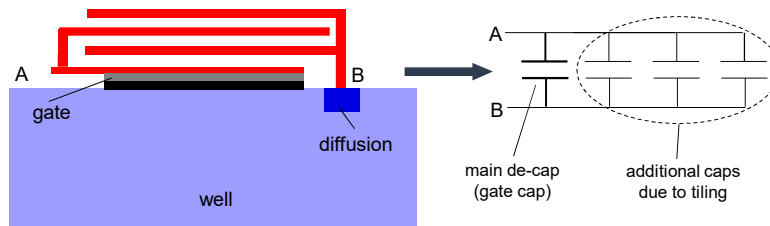


Tiling of matched resistors



## Tiling methodology

- Tiles over de-caps can be connected to the cap terminals to get additional caps



## HV(Power) Layout Design Considerations

- Ron of the driver (Power FET) is quite critical so driver should be sized carefully
  - Total Ron = Ron of driver + routing resistance + bond wire resistance

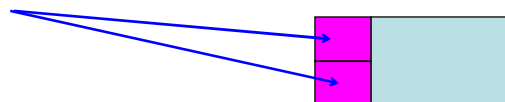
- Driver occupies large portion of the die so inner bonding could be used to reduce the area

- Bond over Active (not supported by all processes) helps in reducing area and Ron

also



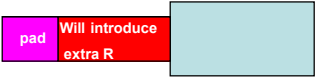

- Multi bonding techniques can be used to reduce the total Ron



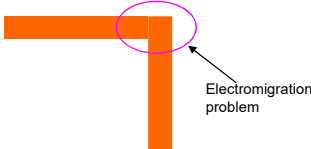
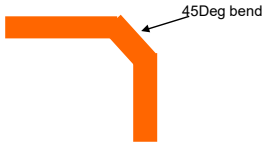


## HV Layout Design Considerations


- Driver should be placed closest to the pad to reduce  $R_{on}$  and hence  $I^2R$  heat dissipation

- High current carrying metal lines should be bent at 45deg instead of 90deg to avoid the electromigration

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## HV Layout Design Considerations

- LV, MV, HV circuits should be separated with the guard bars

MV

HV

PISO

BLK1


LV

BLK2

Sub-blocks of the same voltage ckts should be place together

- ESDs and clamping diodes should be placed at input to the chip

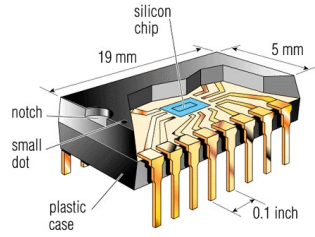
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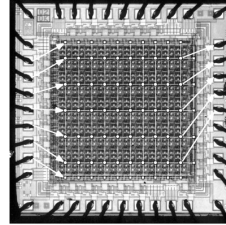
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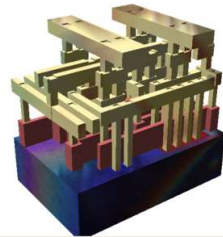
# Chip Snapshots



Package



Bonding



A 3-metal silicon chip

